



In the United States Patent and Trademark Office

Applicant: Zhang

Application No: 10/743,963

Filed: December 22, 2003

For: CHEMICAL MECHANICAL
PLANARIZATION (CMP) SYSTEM AND
METHOD FOR PREPARING A WAFER IN A
CLEANING MODULE

)
) Examiner: RACHUBA, M.
)
) Art Unit: 3723
)
) Date: May 10, 2006
)
) Attorney Docket No.: LAM2P456

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450 on May 10, 2006.

Signed: 

Melinda M. Ward

Separate Letter to the Official Draftsperson

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed herewith are the six (6) sheets of Formal Drawings (Figs. 1, 2A, 2B, 2C, 3A, 3B, 4A and 4B) for the above-referenced case. If the draftsperson has any questions concerning these drawings, please contact the undersigned at the number set forth below.

Applicant believes that no fees are due in connection with the filing of the Formal Drawings. However, if it is determined that any fees are due in connection with the filing of these drawings, the Commissioner is authorized to charge such fees to deposit account 50-0805 (Order No. LAM2P456).

Respectfully submitted,
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